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Docket No.: 1514.1032

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

PARK, Ji Yong et al.

Serial No. 10/690,507

Group Art Unit: 1765

Confirmation No. 6043

Filed: October 23, 2003

Examiner: Unassigned

For: METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND
THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN
FILM MANUFACTURED BY THE MANUFACTURING METHOD

PRELIMINARY AMENDMENT

Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

Sir:

Before examination of the above-identified application, please amend the application as follows:

IN THE TITLE:

Please DELETE the Title in its entirety and substitute the attached new Title.

METHOD FOR MANUFACTURING POLYCRYSTALLINE SILICON THIN FILM AND
THIN FILM TRANSISTOR FABRICATED USING POLYCRYSTALLINE SILICON THIN FILM
MANUFACTURED BY THE MANUFACTURING METHOD